



2823

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Koji SUZUKI

Application No.: 09/970,763

Filed: October 5, 2001

For: METHOD FOR MONITORING DEPOSITION REACTION DURING PROCESSING
THE SURFACE OF A SEMICONDUCTOR SUBSTRATE (AS AMENDED)

Group Art Unit: 2823

Examiner: B. Kebede

Docket No.: 110596

RECEIVED
SEP 17 2003
TECHNOLOGY CENTER 2800

AMENDMENT UNDER 37 C.F.R. §1.111

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed June 23, 2003, the following is submitted:

Amendments to the Specification; and

Remarks.

Amendments to the Specification

Please replace the title as follows:

~~APPARATUS AND METHOD~~METHODS FOR MONITORING DEPOSITION
REACTION DURING PROCESSING THE SURFACE OF A SEMICONDUCTOR
SUBSTRATE